

Silicon Sensors & Actuators

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Cover photograph of Analog Devices Gyroscope.

1	INTRODUCTION	1
1.1.	Introduction	1
1.2	Measurement and control systems	2
1.3	Transducers	4
1.3.1	<i>Form of signal-carrying energy</i>	4
1.3.2	<i>Signal conversion in transducers</i>	7
1.3.3	<i>Terminology in the transducer field</i>	9
1.3.4	<i>Self-generating and modulating transducers</i>	13
1.3.5	<i>Representation of input and output transducers</i>	14
1.3.6	<i>Signal conversion inside modifiers</i>	16
1.4	Transducer technologies	16
1.4.1	<i>Introduction</i>	16
1.4.2	<i>Non-silicon generic technologies</i>	17
1.4.3	<i>Silicon</i>	19
1.5	Future outlook on measurement and control systems	22
1.5.1	<i>Traditional products</i>	22
1.5.2	<i>Present innovative markets</i>	23
1.5.3	<i>Future innovative markets</i>	23
1.6	Read-out.....	24
1.6.1	<i>Frequency output</i>	25
Ring oscillator	25	
Resonator strucures	26	
1.6.2	<i>Stochastic analogue-to-digital converters</i>	26
1.6.3	<i>Offset and cross-sensitivity</i>	27
1.7	Book overview	28
1.8	Conclusions.....	28
1.9	References.....	28
2	RADIATION SENSORS	31
2.1.	Introduction	31
2.1.1	<i>Electromagnetic radiation</i>	31
2.1.2	<i>Nuclear-particle radiation</i>	33
2.2	Basic physical principles	34
2.2.1	<i>Characterization of electromagnetic and nuclear particle energy and their interactions with substances</i> 34	
Reflection, refraction and transmission	35	

<i>Absorption</i>	36
<i>Interference and diffraction</i>	37
<i>Polarization</i>	37
<i>Energy, flux and intensity measurements</i>	38
<i>The colour triangle</i>	40
2.2.2 <i>Interactions of electromagnetic radiation with silicon</i>	41
<i>Interactions of electromagnetic radiation with bulk silicon</i>	41
<i>pn-junctions</i>	50
<i>Schottky-barrier contacts</i>	61
<i>Metal-insulator-semiconductor structures</i>	64
2.2.3 <i>Interaction of nuclear particles with silicon</i>	70
<i>Interaction with bulk silicon</i>	70
<i>Interaction of nuclear particles with junctions</i>	71
2.3 Applications for visible light	72
2.3.1 <i>Photoconductors</i>	72
2.3.2 <i>Photodiodes</i>	74
2.3.3 <i>Avalanche photodiodes</i>	77
2.3.4 <i>P-I-N photodiodes</i>	79
2.3.5 <i>Quadrant photodiodes</i>	81
2.3.6 <i>Position-sensitive detectors</i>	82
<i>Sun-position photodetectors</i>	82
<i>Position-sensitive photodetector (PSD)</i>	83
2.3.7 <i>One- and two-dimensional photodiode arrays\</i>	86
2.3.8 <i>Phototransistors</i>	88
2.3.9 <i>Charge-transfer devices</i>	89
2.3.10 <i>CMOS Image Sensors</i>	91
2.3.11 <i>UV detectors</i>	92
2.4 Applications for nuclear-particle radiation	92
2.4.1 <i>Nuclear-particle radiation detectors</i>	92
2.4.2 <i>Silicon Carbide X-Ray detector</i>	95
2.4.3 <i>Silicon-microstrip detector</i>	95
2.4.4 <i>Silicon-drift chamber</i>	97
2.5 Applications for X- and gamma-rays	98
2.6 References	99
3 MECHANICAL SENSORS	107
3.1 Introduction	107
3.2 Basic physical principles	109

3.2.1	<i>The piezoresistive effect</i>	109
Metals	110	
Silicon	113	
Polycrystalline and amorphous silicon	130	
3.2.2	<i>Other stress-sensitive silicon devices</i>	132
The piezojunction effect	132	
Tunnel-diode pressure sensors	134	
Pressure sensitive MOSFETs	135	
3.2.3	<i>Piezoelectricity</i>	137
Silicon is non-piezoelectric	137	
Use of piezoelectric layers	139	
3.2.4	<i>Mechanics of cantilevers and diaphragms</i>	141
Elastic properties of silicon	141	
Cantilevers	142	
Diaphragms	144	
Capacitive pressure sensors	149	
3.2.5	<i>Surface acoustic wave transducers</i>	151
3.3	<i>Applications of silicon mechanical sensors</i>	155
3.3.1	<i>Silicon strain gauges</i>	155
Diffused diaphragm pressure sensors	156	
3.3.2	<i>Accelerometers</i>	159
3.3.3	<i>Silicon gyroscopes</i>	162
3.3.4	<i>Silicon tactile sensors for robot applications</i>	165
3.4	<i>References</i>	167
4	THERMAL SENSORS	173
4.1	<i>Introduction</i>	173
4.2	<i>Basic physical principles</i>	174
4.2.1	<i>Thermoelectric effects</i>	174
The Seebeck effect	175	
The Peltier effect	191	
The Thomson effect	193	
Kelvin relations	195	
4.2.2	<i>Thermo resistors</i>	197
Metal thermoresistors	198	
Semiconducting thermoresistors	200	
Silicon spreading resistance temperature sensor	206	
4.2.3	<i>Silicon diodes and transistors as thermal sensors</i>	209
Diodes	210	

<i>Transistors</i>	212
4.3 Applications of silicon thermal sensors	214
4.3.1 Thermal flow sensors	215
4.3.2 Vacuum sensors	217
4.3.3 Thermal infrared sensors	219
<i>Integrated PTAT temperature sensors</i> 222	
4.4 References	225
5 MAGNETIC SENSORS	229
5.1. Introduction	229
5.2 Basic physical principles	231
5.2.1 <i>Hall effect and magnetoresistivity</i>	231
<i>Hall effect in metals</i> 232	
<i>Hall effect in semiconductors</i> 235	
<i>Magnetoresistivity in semiconductors and magnetic layers</i> 241	
5.2.2 <i>Silicon Hall plates</i>	247
<i>Silicon technology for Hall devices</i> 247	
<i>Sensitivity of Hall plates</i> 249	
<i>Geometrical correction factor</i> 253	
<i>Offset</i> 254	
<i>Other properties of Hall plates</i> 260	
5.2.3 <i>Magnetodiodes</i>	260
5.2.4 <i>Magnetotransistors</i>	263
<i>Lateral magnetotransistors</i> 264	
<i>Vertical magnetotransistors</i> 266	
<i>MOSFET magnetotransistors</i> 268	
5.2.5 <i>Carrier-domain magnetic-field sensors</i>	272
5.2.6 <i>Applications of magnetic field sensors.</i>	275
5.2.7 <i>Magnetic field measurements.</i>	275
<i>Field measurements with Hall plates</i> 275	
<i>Measurement of electric current with Hall plates.</i> 276	
<i>Three-dimensional field mapping</i> 277	
<i>Magnetic recording heads</i> 279	
5.2.8 <i>Proximity and angle detectors</i>	279
<i>Hall multipliers</i> 282	
5.3 References	283

6 CHEMICAL SENSORS	287
6.1.Introduction	287
6.2Basic physical principles	291
6.2.1 <i>Chemo-resistors and chemo-capacitors</i>	291
6.2.2 <i>Tinoxide gas sensor</i>	291
<i>Polymer chemo-resistors and chemo-capacitors</i> 293	
6.2.3 <i>Chemdiodes</i>	295
<i>The ion-controlled diode</i> 296	
<i>Schottky diodes as chemical sensors</i> 297	
6.2.4 <i>MOSFET-based chemical sensors</i>	299
<i>The ADFET</i> 303	
<i>Pd-gate MOSFET gas sensors</i> 304	
<i>Ion-sensitive field-effect transistors</i> 306	
6.2.5 <i>Humidity sensors</i>	312
<i>Integrated capacitive humidity sensor</i> 313	
<i>Humidity-sensitive MOSFET structure</i> 315	
<i>Integrated dew-point humidity sensor</i> 317	
6.2.6 <i>Integrated oxygen sensors</i>	319
6.3Applications	322
6.3.1 <i>Biosensors</i>	323
6.4Silicon-wafer gas chromatograph	325
6.5References.....	327
7 DEVELOPMENT OF ACTUATORS	333
7.1.Introduction	333
7.2The Development of Classical Mechanical Actuators.....	335
7.2.1 <i>Electromagnetic actuators</i>	340
7.3Transfer of mechanical energy.....	343
7.3.1 <i>Using the mechanical medium</i>	343
7.3.2 <i>Using a fluid medium</i>	344
7.4Power Electronics	349
7.4.1 <i>Isolation techniques</i>	350
7.4.2 <i>Protection circuits</i>	352
7.5Conclusions.....	354
7.6References.....	354

8 ACTIVATION TECHNIQUES	357
8.1.Introduction	357
8.2Piezoelectric effect	357
8.3Electrostrictive effect.....	366
8.4Electromagnetic effect.....	369
8.5Electrostatic effect	370
8.6Magnetostriction effect.....	371
8.7Magnetoelastic effect.....	373
8.8Thermal effect.....	373
8.8.1 <i>Shape memory alloys</i>	374
8.9Optical Actuators.....	376
8.10Conclusions	379
8.11References	379
9 SILICON MICRO-ACTUATORS	383
9.1.Introduction	383
9.2Micromachining techniques	385
9.3Microactuator structures.....	389
9.3.1 <i>Micromotor</i>	389
9.3.2 <i>Micropumps</i>	392
9.3.3 <i>Considerations of microfluidics</i>	402
9.3.4 <i>Examples of micropumps</i>	405
9.3.5 <i>Micromanipulators and placement actuators</i>	408
9.4Actuators for Optical Signals	410
9.5Conclusions	413
9.6References	413
10 SENSOR & ACTUATOR TECHNOLOGY	421
10.1.Silicon planar technology	421
10.1.1 <i>Introduction</i>	421
10.1.2 <i>Device technologies</i>	423
10.1.3 <i>Basic silicon planar-processing steps</i>	426
<i>Crystal growth</i> 427	
<i>Epitaxial growth</i> 429	

<i>Thermal oxidation of silicon</i>	430
<i>Lithography</i>	433
<i>Etching procedures</i>	434
<i>Diffusion</i>	436
<i>Ion-implantation</i>	438
<i>Silicon dioxide, silicon nitride and polysilicon deposition</i>	440
<i>Metallisation and interconnections</i>	442
<i>Circuit testing, bonding and encapsulation</i>	443
10.1.4 <i>Special requirements for silicon-sensor processing</i>	444
<i>Bonding</i>	447
10.2 <i>Compatible technologies</i>	454
10.2.1 <i>Thin-film deposition</i>	454
10.2.2 <i>ZnO thin-film deposition</i>	456
10.2.3 <i>Thick-films deposition</i>	457
10.2.4 <i>Magnetic-film deposition</i>	457
10.2.5 <i>Graphene</i>	459
10.2.6 <i>Polymers/Ceramics</i>	459
10.3 <i>Micromachining technologies</i>	460
10.3.1 <i>Introduction</i>	460
10.3.2 <i>Etching solutions and gasses</i>	461
10.3.3 <i>Bulk micromachining</i>	463
<i>Wet etching</i> 463	
<i>Dry etching</i> 467	
10.3.4 <i>Surface micromachining</i>	469
10.3.5 <i>Epi micromachining</i>	472
<i>SCREAM</i> 473	
<i>SIMPLE</i> 475	
<i>SIMOX</i> 476	
<i>MELO</i> 477	
<i>Porous silicon</i> 479	
<i>Epi-poly</i> 481	
10.3.6 <i>LIGA process</i>	483
10.3.7 <i>Micromachined structures</i>	484
10.3.8 <i>Devices fabricated with micromachining technologies</i>	486
10.4 <i>References</i>	487
A APPENDICES	503
1.2 <i>Sensor characteristics</i>	508